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Interferometry XV: Techniques and Analysis

**Catherine E. Towers
Joanna Schmit
Katherine Creath**
Editors

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The CID number appears on each page of the manuscript. The complete citation is used on the first page, and an abbreviated version on subsequent pages. Numbers in the index correspond to the last two digits of the six-digit CID number.

Contents

ix	Conference Committee
xi	Introduction

SESSION 1 SPACE OPTICS

- 7790 02 **Survey of interferometric techniques used to test JWST optical components (Invited Paper)** [7790-01]
H. P. Stahl, NASA Marshall Space Flight Ctr. (United States); C. Alongi, A. Arneson, R. Bernier, L-3 Communications Tinsley Labs. Inc. (United States); B. Brown, D. Chaney, Ball Aerospace Technology Corp. (United States); G. Cole, NASA Contract Assurance Services (United States); J. Daniel, L. Dettmann, L-3 Communications Tinsley Labs. Inc. (United States); R. Eng, NASA Marshall Space Flight Ctr. (United States); B. Gallagher, Ball Aerospace Technology Corp. (United States); R. Garfield, L-3 Communications Tinsley Labs. Inc. (United States); J. Hadaway, The Univ. of Alabama in Huntsville (United States); P. Johnson, A. Lee, L-3 Communications Tinsley Labs. Inc. (United States); D. Leviton, NASA Goddard Space Flight Ctr. (United States); A. Magruder, L-3 Communications Tinsley Labs. Inc. (United States); M. Messerly, Lawrence Livermore National Lab. (United States); A. Patel, L-3 Communications Tinsley Labs. Inc. (United States); P. Reardon, The Univ. of Alabama in Huntsville (United States); J. Schwenker, Ball Aerospace Technology Corp. (United States); M. Seilonen, L-3 Communications Tinsley Labs. Inc. (United States); K. Smith, Ball Aerospace Technology Corp. (United States); W. S. Smith, NASA Marshall Space Flight Ctr. (United States)
- 7790 04 **Cryogenic wavefront error measurement for the James Webb Space Telescope fine-guidance sensor-powered optics** [7790-03]
C. E. Evans, E. S. Greenberg, D. A. Aldridge, COM DEV Canada (Canada); J. J. Santman, Corning NetOptix (United States)
- 7790 05 **Dual frequency sweeping interferometry for absolute distance metrology at long ranges: implementation and performance** [7790-04]
A. Cabral, M. Abreu, J. M. Rebordão, V. Oliveira, Univ. de Lisboa (Portugal)

SESSION 2 PHASE MEASURING ALGORITHMS AND EXTENDED RANGE MEASUREMENTS

- 7790 06 **Extended averaging phase-shift schemes for Fizeau interferometry on high-numerical-aperture spherical surfaces (Invited Paper)** [7790-05]
J. Burke, Commonwealth Scientific and Industrial Research Organisation (Australia)
- 7790 07 **Real-time phase demodulation of heterodyne speckle interference patterns using correlation image sensor** [7790-06]
A. Kimachi, Osaka Electro-Communication Univ. (Japan)
- 7790 08 **Linear systems theory for the analysis of phase-shifting algorithms** [7790-07]
J. C. Estrada, M. Servin, Ctr. de Investigaciones en Óptica, A.C. (Mexico); J. A. Quiroga, Univ. Complutense de Madrid (Spain)

- 7790 09 **Theoretical analysis and optimisation of the method of excess fractions for long-range metrology** [7790-08]
K. Falaggis, D. P. Towers, C. E. Towers, Univ. of Leeds (United Kingdom)

SESSION 3 FRINGE PROJECTION AND REFLECTION METHODS

- 7790 0A **Uni-axial measurement of three-dimensional surface profile by liquid crystal digital shifter** [7790-10]
Y. Otani, F. Kobayashi, Utsunomiya Univ. (Japan); Y. Mizutani, The Univ. of Tokushima (Japan); S. Watanabe, M. Harada, Malcom Co., Ltd. (Japan); T. Yoshizawa, Saitama Medical Univ. (Japan)
- 7790 0B **Generating sinusoidal fringe by defocusing: potentials for unprecedentedly high-speed three-dimensional shape measurement using a DLP projector** [7790-11]
J. Li, S. Zhang, Iowa State Univ. (United States)
- 7790 0C **A compact LED-based phase measuring deflectometry setup** [7790-12]
P. Lehtonen, VTT Technical Research Ctr. of Finland (Finland); Y. Liu, Sichuan Univ. (China)
- 7790 0D **Fast and flexible calibration of a phase-based three-dimensional imaging system by uneven fringe projection** [7790-13]
Z. Zhang, Hebei Univ. of Technology (China); T. Guo, Tianjin Univ. (China); S. Zhang, Hebei Univ. of Technology (China); X. Fu, X. Hu, Tianjin Univ. (China); C. E. Towers, D. P. Towers, Univ. of Leeds (United Kingdom)
- 7790 0E **Three-dimensional microstructure measurement by high-resolution fringe analysis for shadow moiré image by SEM** [7790-14]
Y. Arai, S. Kanameishi, Kansai Univ. (Japan); S. Yokozeki, Jyouko Applied Optics Lab. (Japan)

SESSION 4 CALIBRATION METHODS

- 7790 0F **Self-referencing calibration method for transmission spheres in Fizeau interferometry** [7790-15]
J. Burke, Commonwealth Scientific and Industrial Research Organisation (Australia); D. S. Wu, The Univ. of Sydney (Australia)
- 7790 0G **Self-calibrating lateral scanning white-light interferometer** [7790-16]
F. Munteanu, Veeco Metrology Inc. (United States)
- 7790 0H **Discrete step wavemeter** [7790-17]
C. Aleksoff, Coherix Corp. (United States); H. Yu, Univ. of Michigan (United States)
- 7790 0I **Frequency-stepping interferometry for accurate metrology of rough components and assemblies** [7790-18]
T. J. Dunn, C. A. Lee, M. J. Tronolone, Corning Tropel Corp. (United States)

SESSION 5 OPTICAL SURFACE TESTING

- 7790 0J **Precision interferometry in less than ideal environments (Keynote Paper)** [7790-19]
J. C. Wyant, College of Optical Sciences, The Univ. of Arizona (United States)
- 7790 0K **The spatial frequency response and resolution limitations of pixelated mask spatial carrier based phase shifting interferometry** [7790-20]
B. Kimbrough, J. Millerd, 4D Technology Corp. (United States)
- 7790 0L **Imaging issues for interferometric measurement of aspheric surfaces using CGH null correctors (Invited Paper)** [7790-21]
P. Zhou, J. Burge, C. Zhao, College of Optical Sciences, The Univ. of Arizona (United States)
- 7790 0M **An analytic expression for the field dependence of FRINGE Zernike polynomial coefficients in rotationally symmetric optical systems** [7790-22]
J. P. Rolland, C. Dunn, Univ. of Rochester (United States); K. P. Thompson, Optical Research Associates (United States)

SESSION 6 SPECKLE AND HOLOGRAPHIC TECHNIQUES

- 7790 0N **Theoretical and experimental investigation of statistics of spatial derivatives of Stokes parameters for polarization speckle** [7790-23]
S. Zhang, Heriot-Watt Univ. (United Kingdom); P. Roulleau, Univ. de Poitiers (France); A. Matsuda, M. Takeda, The Univ. of Electro-Communications (Japan); W. Wang, Heriot-Watt Univ. (United Kingdom)
- 7790 0O **Noise reduction in dynamic interferometry measurements** [7790-24]
M. North Morris, M. Naradikian, J. Millerd, 4D Technology Corp. (United States)
- 7790 0Q **Three-dimensional coherence holography using a commercial projector for display and incoherent illumination of a coherence hologram** [7790-26]
D. N. Naik, T. Ezawa, R. K. Singh, Y. Miyamoto, M. Takeda, The Univ. of Electro-Communications (Japan)

SESSION 7 MICRO-ELEMENT MEASUREMENT AND IMAGE REGISTRATION TECHNIQUES

- 7790 0R **Low-cost full-field microinterferometer heads produced by hot- embossing technology (Invited Paper)** [7790-27]
M. Kujawinska, J. Krezel, R. Krajewski, Warsaw Univ. of Technology (Poland)
- 7790 0S **Image continuity at different levels of zoom for Moiré techniques** [7790-28]
M. Abolbashari, A. S. Gerges, A. Davies, F. Farahi, The Univ. of North Carolina at Charlotte (United States)

SESSION 8 SPECTRAL METHODS AND OPTICAL SECTIONING

- 7790 0T **High-speed optical coherence imaging: towards the structure and the physiology of living tissue (Invited Paper)** [7790-31]
M. Wojtkowski, I. Grulkowski, A. Szkulmowska, M. Szkulmowski, A. Kowalczyk, Nicolaus Copernicus Univ. (Poland)

- 7790 0U **Multiple-wavelength interferometers using backpropagation of optical fields for profile measurement of thin glass sheets** [7790-32]
O. Sasaki, S. Choi, T. Suzuki, Niigata Univ. (Japan)
- 7790 0V **Comparison of different film thickness evaluation algorithms applicable to spectrometric interrogation systems** [7790-33]
F. Hirth, A. Pérez Grassi, D. G. Dorigo, A. W. Koch, Technische Univ. München (Germany)
- 7790 0W **Fiber optical interferometric sensor based on a piezo-driven oscillation** [7790-34]
M. Schulz, P. Lehmann, J. Niehues, Univ. Kassel (Germany)

SESSION 9 MATERIAL PROPERTY MEASUREMENTS

- 7790 0X **Spectroscopy with a coherent dual frequency comb interferometer at 3.4 μm (Invited Paper)** [7790-35]
E. Baumann, F. R. Giorgetta, I. Coddington, W. C. Swann, N. R. Newbury, National Institute of Standards and Technology (United States)
- 7790 0Y **Simultaneous measurement of spectral reflectivity and birefringence of a stone surface using polarization phase-shifting interferometer** [7790-36]
H. Kobayashi, I. Ishimaru, Kagawa Univ. (Japan)
- 7790 0Z **Determination of refractive index of transparent plate by Fabry-Perot fringe analysis** [7790-37]
H. J. Choi, H. H. Lim, H. S. Moon, Pusan National Univ. (Korea, Republic of); T. B. Eom, Korea Research Institute of Standards and Science (Korea, Republic of); J. J. Ju, Electronics and Telecommunications Research Institute (Korea, Republic of); M. Cha, Pusan National Univ. (Korea, Republic of)
- 7790 10 **Measurement of surface resistivity/conductivity of carbon steel in 5-20ppm of RA-41 inhibited seawater by optical interferometry techniques** [7790-38]
K. Habib, Kuwait Institute for Scientific Research (Kuwait)

POSTER SESSION

- 7790 11 **Non-steady-state photo-EMF effect induced by an arbitrary 1D periodical light distribution** [7790-40]
I. Guízar-Iturbide, Instituto Nacional de Astrofísica, Óptica y Electrónica (Mexico);
L. G. de la Fraga, Ctr. de Investigación y de Estudios Avanzados (Mexico);
P. Rodríguez-Montero, S. Mansurova, Instituto Nacional de Astrofísica, Óptica y Electrónica (Mexico)
- 7790 12 **Large-optics shearing interferometer for the wavefront sensing of widely tunable laser** [7790-41]
Z. Luan, L. Wang, Y. Zhou, E. Dai, J. Sun, L. Liu, Shanghai Institute of Optics and Fine Mechanics (China)
- 7790 13 **Polarized point diffraction interferometer for fringe stabilization** [7790-42]
H. Kihm, Y.-W. Lee, Korea Research Institute of Standards and Science (Korea, Republic of)

- 7790 14 **Wavefront calculation from backscattering phase in optical rough elements** [7790-43]
G. Díaz-Gonzalez, J. Muñoz-Lopez, J. Castro-Ramos, Instituto Nacional de Astrofísica, Óptica y Electrónica (Mexico); A. Santiago-Alvarado, Univ. Tecnológica de la Mixteca (Mexico)
- 7790 15 **Investigation of three-beam interference fringes with controllable phase shift of two reference waves** [7790-44]
M. A. Volynsky, I. P. Gurov, Saint-Petersburg State Univ. of Information Technologies, Mechanics and Optics (Russian Federation)
- 7790 16 **One-shot in-line digital-holography-based two-dimensional Hilbert demodulation technique** [7790-45]
W. Pan, Y. Zhu, Y. Fan, Zhejiang Science and Technology Univ. (China); H. Lang, Beijing Univ. of Chemical Technology (China)
- 7790 17 **Autofocusing on pure phase object for living cell imaging in lensless Fourier transform digital holography** [7790-46]
J. Zhao, D. Wang, Y. Wang, C. Liu, Y. Li, H. Cui, Y. Wan, Beijing Univ. of Technology (China)
- 7790 18 **Adaptive photodetector versus conventional method for localization of the Talbot self-images** [7790-47]
I. Guízar-Iturbide, Instituto Nacional de Astrofísica, Óptica y Electrónica (Mexico); L. G. de la Fraga, Ctr. de Investigación y de Estudios Avanzados (Mexico); P. Rodríguez-Montero, S. Mansurova, Instituto Nacional de Astrofísica, Óptica y Electrónica (Mexico)
- 7790 19 **Wave-front reconstruction by digital phase retrieval method in high power laser** [7790-49]
W. Huang, D. Liu, X. Zhang, Y. Zhang, J. Zhu, Shanghai Institute of Optics and Fine Mechanics (China)
- 7790 1A **Improving four-dimensional shape measurement by using projector defocusing** [7790-50]
Y. Gong, S. Zhang, Iowa State Univ. (United States)
- 7790 1B **A new color structured light coding method for three-dimensional measurement of isolated objects** [7790-52]
K. Ma, Q. Zhang, Sichuan Univ. (China)
- 7790 1C **A fast three-dimensional shape measurement based on two orthogonal grating projection** [7790-53]
X. Su, Y. Dou, Q. Zhang, L. Xiang, Sichuan Univ. (China)

Author Index

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- 3 Fringe Projection and Reflection Methods
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- 4 Calibration Methods
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- 5 Optical Surface Testing
Mitsuo Takeda, The University of Electro-Communications (Japan)
- 6 Speckle and Holographic Techniques
Conrad Wells, ITT Corporation (United States)
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- 9 Material Property Measurements
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Introduction

We thank SPIE, the program committee, the authors, and everyone attending this fifteenth Interferometry conference. SPIE continues to provide a forum for exchange of ideas and the dissemination of the latest research in interferometry and related fields. As a community we come together at conferences such as this one to share not only our work, but also our professional vision. We reacquaint ourselves with old friends and meet new colleagues. The value of these conferences comes from both the professional insight we gain and the relationships we foster.

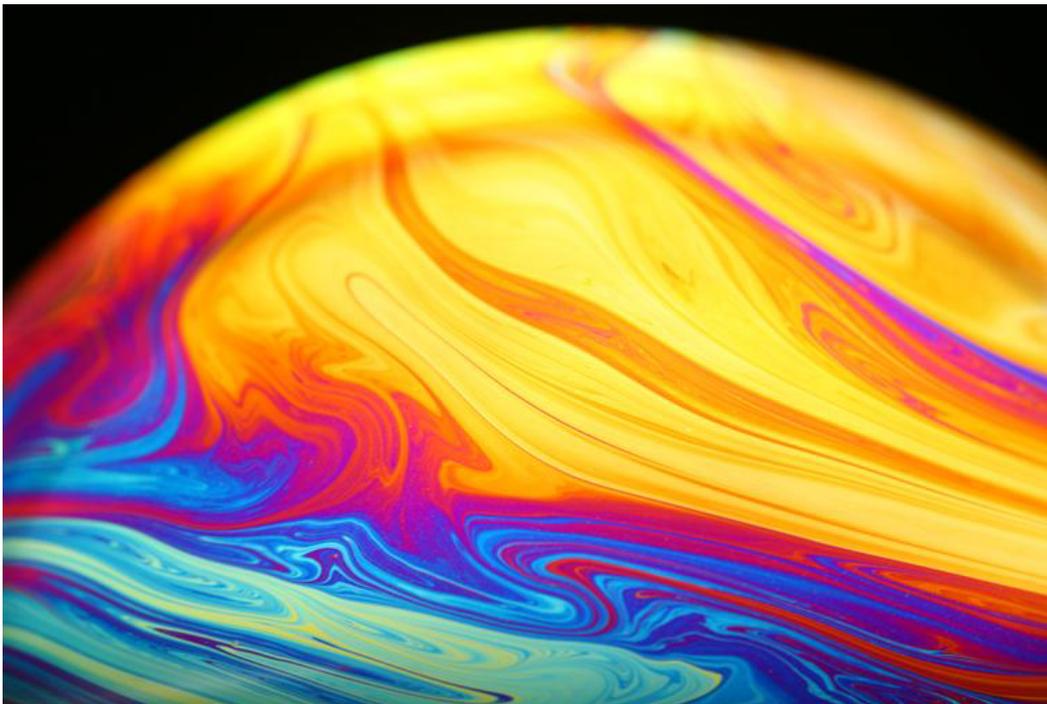
Interferometry XV, which is a continuation of the Interferometry series, consists of two complementary conferences, one dedicated to Techniques and Analysis and the other to Applications. These two conferences present recent developments in analyses and techniques that use interference and projection fringes for highly precise measurements of different objects and their application in a wide range of systems. The proceedings of the two conferences comprising Interferometry XV are published in two separate volumes as Interferometry XV: Techniques and Analysis (SPIE Proceedings 7790) and Interferometry XV: Applications (SPIE Proceedings 7791).

The growing demand for accurate and repeatable measurements of increasingly complex devices, especially in the semiconductor and MEMS industries as well as the bio- and outer space sciences has driven the field of optical metrology to develop innovative techniques that provide fast, precise, real-time assessments of a wide array of objects. While the range of techniques and technologies in interferometry is already vast, researchers strive to find solutions to new challenges that help make invisible things visible and to extend our vision further into outer space as well as closer into the nano- and biological worlds.

This conference on Interferometric Techniques and Analysis highlights developments in surface metrology and material properties, digital holography, speckle, temporal and spatial phase shifting, low coherence interferometry, multiple wavelength and fringe projection and reflection and also moiré techniques. Other topics include new developments in calibration methods for interferometric techniques, new ways to measure of aspheric surfaces, and measuring surfaces in less than ideal environments.

We are pleased to present a conference with such a large number of excellent papers. This proceedings volume contains 47 papers presented at the SPIE 55th Annual Meeting in San Diego on August 1-5, 2010. Thirty-seven of these papers were presented orally. These papers represent the work of researchers from 14 countries and four continents.

During our last conference in 2008 we had again a great time choosing our favorite fringe patterns from those submitted by attendees. Every year we receive more and more and very creative submissions. The last conference's favorite *Fringe Art* was of fringes on a soap bubble illuminated by light incident at angles higher than 80° . This resulted in very strong and vibrant color fringe patterns as can be seen in the winning fringe pattern below.



This fringe pattern was photographed by Santiago Betancur for Melissa Palacio students from Universidad Nacional de Colombia Sede Medellín, Optics Group – SPIE Student Chapter. We enthusiastically support and encourage artistic and scientific abilities in students and young researchers. And, of course, we look forward to more stunning submissions.

Many of us are drawn to the images of fringes in our everyday lives, for observing fringes in our surroundings is, one may say, our professional deviation. With this years' conference we have continued the biannual "Fringe Art" competition to share our favorite fringe patterns. The winner will be announced in the next conference proceedings.

Until the next Interferometry conference, may you continue to see fringe patterns everywhere.

Catherine E. Towers
Joanna Schmit
Katherine Creath

